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2-11-99  
PATENT  
8565D-7213

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

FUKAMI, Teruaki

Serial No: 09/218,997

Filed: December 22, 1998

For: SILICON WAFER STORAGE  
WATER AND SILICON WAFER  
STORAGE METHOD

Art Unit: 1712

Examiner: NOT ASSIGNED

**TRANSMITTAL OF INFORMATION DISCLOSURE  
STATEMENT**

Assistant Commissioner for Patents  
Washington, D.C. 20231

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:  
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2/8/99  
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Dear Sir:

The information disclosure statement submitted herewith contains no items of information cited in any communication from a foreign patent office in a counterpart foreign application [37 C.F.R. § 1.97(e)(1)].

If it should be determined that for any reason either an insufficient or excessive fee has been paid, please charge any insufficiency or credit any overpayment necessary to ensure consideration of the information disclosure statement for the above-identified application to Deposit Account No. 12-1820. A copy of this paper is enclosed.

Respectfully submitted,

LOEB & LOEB LLP

Date: February 8, 1999

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